

## Ion Beam Source IBS - 700

Extended ion source IBS-700 is a gas-discharge source of working gas ions with an energy of 500-2500 eV. The principle of operation is an accelerator with an anode layer (UAS).

IBS-700 is designed for a wide range of applications: ion cleaning, etching, polishing, surface modification



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Parameter	Value
Beam shape	rectangular, hollow
Beam size (L x W x T) <i>Length x Width x Thickness</i>	650 x 42 x 5 mm
Supply voltage	500 – 5000 V

*The average ion energy of the beam is approximately equal to half the supply voltage*

Maximum beam current	1000 mA
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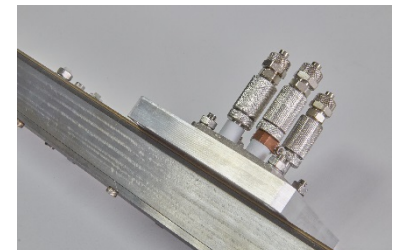
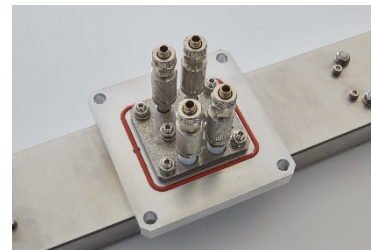
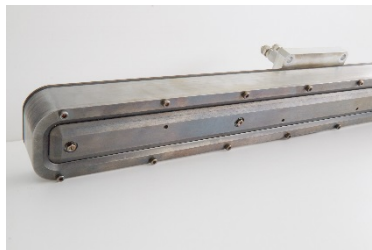
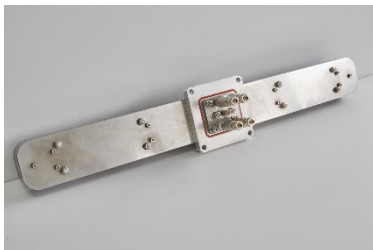
*For working gas (argon)*

<i>at a flow rate of not more than</i>	2.0 l / h
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Maximum working pressure in the chamber	10 Pa
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Chamber working pressure range	0,001-1 Pa
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Weight no more than	11,1 kg
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## basic dimensions

